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Jc996 U.S. PTO

PATENT

Docket No. JCLA6211

Date: 1-17-2001

Page 1

Jc841 U.S. PTO  
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01/17/01

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231  
ATTENTION: APPLICATION BRANCH

Sir:

Transmitted herewith for filing is the patent application of

Inventors: Yun-Kuei Yang, Yi- Ming Chang

For: METHOD OF USING ION IMPLANTATION TO FORM OPENINGS IN AN  
INSULATOR

Enclosed are:

- ☒ Specification 14 pages.
- ☒ 6 Sheets of drawings
- ☒ Recordation Form Cover sheet with 2 pages assignment.
- ☐ A certified copy of Taiwan Patent Application No.      dated
- ☒ **SIGNED** declaration and power of attorney.
- ☒ Return Prepaid postcard.

## CLAIMS AS FILED

FOR	NUMBER FILED	NUMBER EXTRA	RATE	FEE
Basic Fee			\$710.00	\$710.00
Total Claims	19 — 20 =	0 ×	\$18.00	\$0.00
Independent Claims	2 — 3 =	0 ×	\$80.00	\$0.00
If application contains any multiple dependent claim (s), then add			\$270.00	\$0.00
TOTAL FILING FEE				\$710.00

- ☒ A check in the amount of \$710 cover the filing fee is enclosed.
- ☒ A check in the amount of \$40.00 to cover the assignment recording fee.
- ☒ A duplicate copy of this sheet is enclosed.

*Jiawei Huang*

Jiawei Huang

Registration No. 43,330